

Day : Thursday
Date: 10/14/2004
Time: 12:03:39

PALM INTRANET

Inventor Name Search Result

Your Search was:

Last Name = ODA

First Name = SHUNRI

Application#	Patent#	Status	Date Filed	Title	Inventor Name 39
<u>10667517</u>	Not Issued	030	09/23/2003	MICRO ELECTRON GUN OF QUANTUM SIZE EFFECT TYPE AND FLAT DISPLAY USING SUCH ELECTRON GUNS AS WELL AS METHODS OF THEIR MANUFACTURE	ODA, SHUNRI
<u>10490660</u>	Not Issued	030	03/25/2004	SOLID-STATE SELF-EMISSION DISPLAY AND ITS PRODUCTION METHOD	ODA, SHUNRI
<u>10275959</u>	<u>6661021</u>	150	11/18/2002	QUANTUM SIZE EFFECT TYPE MICRO ELECTRON GUN AND FLAT DISPLAY UNIT USING IT AND METHOD FOR MANUFACTURING THE SAME	ODA, SHUNRI
<u>08396266</u>	Not Issued	161	02/28/1995	PROCESS FOR FORMING DEPOSITED FILM USING A GAS PHASE METHOD INVOLVING AT LEAST ONE ACTIVATED COMPOUND	ODA, SHUNRI
<u>08218834</u>	Not Issued	166	03/28/1994	PROCESS FOR FORMING A DEPOSITED FILM USING A GAS PHASE METHOD INVOLVING AT LEAST ONE ACTIVATED COMPOUND	ODA, SHUNRI
<u>08041511</u>	Not Issued	166	04/01/1993	PROCESS FOR FORMING DEPOSITED FILM	ODA, SHUNRI
<u>07904904</u>	Not Issued	166	06/23/1992	PROCESS FOR FORMING DEPOSITED FILM	ODA, SHUNRI
<u>07690313</u>	Not Issued	166	04/25/1991	PROCESS FOR FORMING DEPOSITED FILM	ODA, SHUNRI
<u>07685165</u>	<u>5244698</u>	150	04/12/1991	PROCESS FOR FORMING DEPOSITED FILM	ODA, SHUNRI
<u>07507001</u>	<u>5178904</u>	150	04/10/1990	PROCESS FOR FORMING DEPOSITED FILM FROM A	ODA, SHUNRI

				GROUP II THROUGH GROUP VI METAL HYDROCARBON COMPOUND	
<u>07469808</u>	<u>5294285</u>	150	01/22/1990	PROCESS FOR THE PRODUCTION OF FUNCTIONAL CRYSTALLINE FILM	ODA , SHUNRI
<u>07391675</u>	Not Issued	166	08/08/1989	PROCESS FOR FORMING DEPOSITED FILM	ODA , SHUNRI
<u>07338428</u>	Not Issued	166	04/14/1989	PROCESS FOR FORMING DEPOSITED FILM	ODA , SHUNRI
<u>07212096</u>	Not Issued	166	06/27/1988	PROCESS FOR FORMING DEPOSITED FILM	ODA , SHUNRI
<u>07186770</u>	<u>4849249</u>	150	04/25/1988	DEPOSITED FILM FORMING PROCESS AND DEPOSITED FILM FORMING DEVICE	ODA , SHUNRI
<u>07113414</u>	<u>4772486</u>	150	10/27/1987	PROCESS FOR FORMING A DEPOSITED FILM	ODA , SHUNRI
<u>07061003</u>	<u>4726963</u>	150	06/09/1987	PROCESS FOR FORMING DEPOSITED FILM	ODA , SHUNRI
<u>07044778</u>	<u>4798167</u>	150	05/01/1987	APPARATUS FOR PREPARING A PHOTOELECTROMOTIVE FORCE MEMBER HAVING A CONCENTRIC TRIPPLICATE CONDUIT FOR GENERATING ACTIVE SPECIES AND PRECURSOR	ODA , SHUNRI
<u>07012367</u>	Not Issued	166	02/09/1987	PROCESS FOR THE PRODUCTION OF FUNCTIONAL CRYSTALLINE FILM	ODA , SHUNRI
<u>06943071</u>	<u>4728528</u>	150	12/18/1986	PROCESS FOR FORMING DEPOSITED FILM	ODA , SHUNRI
<u>06939229</u>	Not Issued	166	12/08/1986	PROCESS FOR FORMING DEPOSITED FILM	ODA , SHUNRI
<u>06895700</u>	Not Issued	166	08/12/1986	DEPOSITED FILM FORMING PROCESS AND DEPOSITED FILM FORMING DEVICE	ODA , SHUNRI
<u>06843304</u>	<u>4689093</u>	150	03/24/1986	PROCESS FOR THE PREPARATION OF PHOTOELECTROMOTIVE FORCE MEMBER	ODA , SHUNRI
<u>06843277</u>	<u>4702934</u>	150	03/24/1986	ELECTROPHOTOGRAPHIC PHOTOSENSITIVE MEMBER, PROCESS AND APPARATUS FOR THE PREPARATION THEREOF	ODA , SHUNRI
<u>06843236</u>	<u>4803093</u>	150	03/24/1986	PROCESS FOR PREPARING A FUNCTIONAL DEPOSITED FILM	ODA , SHUNRI

<u>06831704</u>	<u>4801468</u>	150	02/21/1986	PROCESS FOR FORMING DEPOSITED FILM	ODA , SHUNRI
<u>06831460</u>	<u>4778692</u>	150	02/20/1986	PROCESS FOR FORMING DEPOSITED FILM	ODA , SHUNRI
<u>06831448</u>	<u>4784874</u>	150	02/20/1986	PROCESS FOR FORMING DEPOSITED FILM	ODA , SHUNRI
<u>06831413</u>	<u>4818563</u>	150	02/20/1986	PROCESS FOR FORMING DEPOSITED FILM	ODA , SHUNRI
<u>06831412</u>	Not Issued	166	02/20/1986	PROCESS FOR FORMING DEPOSITED FILM	ODA , SHUNRI
<u>06831411</u>	<u>4853251</u>	150	02/20/1986	PROCESS FOR FORMING DEPOSITED FILM INCLUDING CARBON AS A CONSTITUENT ELEMENT	ODA , SHUNRI
<u>06829929</u>	Not Issued	166	02/18/1986	PROCESS FOR FORMING DEPOSITED FILM	ODA , SHUNRI
<u>06829928</u>	Not Issued	166	02/18/1986	PROCESS FOR FORMING DEPOSITED FILM	ODA , SHUNRI
<u>06829804</u>	Not Issued	166	02/14/1986	PROCESS FOR FORMING DEPOSITED FILM	ODA , SHUNRI
<u>06829791</u>	Not Issued	166	02/14/1986	PROCESS FOR FORMING A DEPOSITED FILM	ODA , SHUNRI
<u>06829072</u>	<u>4717586</u>	150	02/13/1986	PROCESS FOR FORMING DEPOSITED FILM	ODA , SHUNRI
<u>06828543</u>	Not Issued	166	02/12/1986	PROCESS FOR FORMING DEPOSITED FILM	ODA , SHUNRI
<u>06828256</u>	<u>4716048</u>	150	02/11/1986	PROCESS FOR FORMING DEPOSITED FILM	ODA , SHUNRI
<u>06826898</u>	<u>4717585</u>	150	02/06/1986	PROCESS FOR FORMING DEPOSITED FILM	ODA , SHUNRI

Inventor Search Completed: No Records to Display.

	Last Name	First Name
Search Another:	<input type="text" value="ODA"/>	<input type="text" value="SHUNRI"/>
Inventor	<input type="button" value="Search"/>	

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Day : Thursday
Date: 10/14/2004
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Inventor Name Search Result

Your Search was:

Last Name = ZHAO

First Name = XINWEI

Application#	Patent#	Status	Date Filed	Title	Inventor Name 4
<u>10667517</u>	Not Issued	030	09/23/2003	MICRO ELECTRON GUN OF QUANTUM SIZE EFFECT TYPE AND FLAT DISPLAY USING SUCH ELECTRON GUNS AS WELL AS METHODS OF THEIR MANUFACTURE	ZHAO, XINWEI
<u>10309192</u>	Not Issued	161	12/04/2002	LASER AND METHOD FOR PRODUCTION THEREOF	ZHAO, XINWEI
<u>10275959</u>	<u>6661021</u>	150	11/18/2002	QUANTUM SIZE EFFECT TYPE MICRO ELECTRON GUN AND FLAT DISPLAY UNIT USING IT AND METHOD FOR MANUFACTURING THE SAME	ZHAO, XINWEI
<u>09472894</u>	Not Issued	161	12/28/1999	LASER AND METHOD FOR PRODUCTION THEREOF	ZHAO, XINWEI

Inventor Search Completed: No Records to Display.

Search Another: Inventor	Last Name	First Name
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	<input type="button" value="Search"/>	

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Day : Thursday
Date: 10/14/2004
Time: 12:08:51

Inventor Name Search Result

Your Search was:

Last Name = NISHIGUCHI

First Name = KATSUHIKO

Application#	Patent#	Status	Date Filed	Title	Inventor Name 4
<u>10667517</u>	Not Issued	030	09/23/2003	MICRO ELECTRON GUN OF QUANTUM SIZE EFFECT TYPE AND FLAT DISPLAY USING SUCH ELECTRON GUNS AS WELL AS METHODS OF THEIR MANUFACTURE	NISHIGUCHI, KATSUHIKO
<u>10275959</u>	<u>6661021</u>	150	11/18/2002	QUANTUM SIZE EFFECT TYPE MICRO ELECTRON GUN AND FLAT DISPLAY UNIT USING IT AND METHOD FOR MANUFACTURING THE SAME	NISHIGUCHI, KATSUHIKO
<u>07322205</u>	<u>4990319</u>	150	03/13/1989	PROCESS FOR PRODUCING AMMONIA AND SULFUR DIOXIDE	NISHIGUCHI, KATSUHIKO
<u>07245689</u>	Not Issued	166	09/15/1988	PROCESS FOR PRODUCING AMMONIA AND SULFUR DIOXIDE	NISHIGUCHI, KATSUHIKO

Inventor Search Completed: No Records to Display.

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NISHIGUCHI

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KATSUHIKO

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	Type	Hits	Search Text	DBs	Time Stamp
1	BRS	730	quantum near4 particles	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/27 16:06
2	BRS	3	quantum near4 particles and VHF near3 plasma	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/27 16:09
3	BRS	4	("6181055" "5336902").pn.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/08 13:47
4	BRS	240	VHF near3 plasma	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/08 13:56
5	BRS	5	VHF?band near3 plasma	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/27 16:09
6	BRS	0	("6181055" "5336902").pn. and quantum near4 particle	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/08 13:47
7	BRS	0	("6181055" "5336902").pn. and quantum near4 particles	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/08 13:47
8	BRS	3	VHF near3 plasma with argon	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/08 13:51
9	BRS	2	jp-09007499-\$.did.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/08 13:51
10	BRS	2	jp-08111166-\$.did.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/08 13:52
11	BRS	2	jp-09259795-\$.did.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/08 13:52
12	BRS	2	jp-05206515-\$.did.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/08 13:53
13	BRS	2	jp-10269932-\$.did.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/08 13:53

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14	BRS	1	jp-11135830-\$.did.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/08 13:53
15	BRS	2	jp-06269659-\$.did.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/08 13:54
16	BRS	0	VHF near3 plasma and micro?particles	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/08 13:56
17	BRS	3	VHF near3 plasma and micro adj particles	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/08 13:57
18	BRS	87	VHF near3 plasma and particles	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/08 13:57
19	BRS	80	VHF near3 plasma and particles and substrate	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/08 13:58
20	BRS	48	VHF near3 plasma and particles and substrate and silane	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/08 13:58
21	BRS	3	VHF near3 plasma and particles and substrate and silane and argon and particles with (insulating insulation insulative)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/08 13:59
22	BRS	30	VHF near3 plasma and particles and substrate and silane and argon	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/08 14:03
23	BRS	3	VHF near3 plasma and (Si or silicon) near4 particles and substrate and silane and argon	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/08 14:03
24	BRS	345	438/20.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:24
25	BRS	208	438/117.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 11:58
26	BRS	867	438/770.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 11:58

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27	BRS	104	438/771.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:00
28	BRS	36616	spherical and silicon	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:00
29	BRS	6729	spherical same silicon	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:15
30	BRS	3021	spherical with silicon	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:31
31	BRS	1043	spherical near3 silicon	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:13
32	BRS	252	crystal same silicon same ball	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:01
33	BRS	91	crystal with silicon with ball	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:02
34	BRS	161	spherical near3 silicon and plasma	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:02
35	BRS	11	crystal with silicon with ball and plasma	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:18
36	BRS	416	spherical with silicon and plasma	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:09
37	BRS	112	spherical with silicon and plasma and argon	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:10
38	BRS	42	spherical with silicon and plasma and argon and silane	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:10
39	BRS	45	spherical with silicon and plasma same argon	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:10

	Type	Hits	Search Text	DBs	Time Stamp
40	BRS	34	spherical with silicon and plasma with argon	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:10
41	BRS	4	spherical with silicon and plasma with argon same silane	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:11
42	BRS	7	spherical with silicon and plasma with argon and silane	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:12
43	BRS	147	spherical near3 silicon with layer	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:13
44	BRS	35	spherical near3 silicon with (insulating or insulation)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:14
45	BRS	480	spherical same silicon same crystal	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:16
46	BRS	104	spherical same silicon same crystal and plasma	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:16
47	BRS	253	spherical with silicon same crystal	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:16
48	BRS	0	spherical with silicon same crystal and plasam	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:17
49	BRS	52	spherical with silicon same crystal and plasma	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:17
50	BRS	6	spherical with silicon same crystal and plasma same argon	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:17
51	BRS	3	crystal with silicon with ball and plasma same argon	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:19
52	BRS	939	plasma same argon same silane	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:20

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53	BRS	11	plasma same argon same silane same VHF and silicon	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:38
54	BRS	0	6661021.URPN.	USPAT	2004/10/14 12:23
55	BRS	2	("5336902" "6181055").PN.	USPAT	2004/10/14 12:23
56	BRS	1088	438/22.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:24
57	BRS	631	438/48.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:24
58	BRS	11	plasma same argon same silane same VHF and silicon same (layer insulating insulation film)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:37
59	BRS	8	plasma same argon same silane same VHF same (silicon or Si)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:39
60	BRS	47	(spherical (crystal with ball)) with silicon and plasma same argon	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:32
61	BRS	0	(spherical (crystal with ball)) with silicon and plasma same argon same VHF	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:32
62	BRS	10	(spherical crystal ball) with silicon and plasma same argon same VHF	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:33
63	BRS	14	(spherical crystal ball) same silicon and plasma same argon same VHF	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:34
64	BRS	0	(spherical patrticles ball) same silicon and plasma same argon same VHF	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:34
65	BRS	209	(spherical patrticles ball) same silicon and plasma same argon	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:34
66	BRS	101	(spherical patrticles ball) with silicon and plasma same argon	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:35

	Type	Hits	Search Text	DBs	Time Stamp
67	BRS	9	(spherical particles ball) with silicon and plasma same argon same silane	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:35
68	BRS	11	plasma same argon same silane same VHF	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:35
69	BRS	8	plasma same argon same silane same VHF and silicon same (layer insulating insulation film) same (diffuse diffusing diffused diffusion)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:37
70	BRS	1	plasma same argon same silane same VHF and silicon with (diffuse diffusing diffused diffusion)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:38
71	BRS	1	plasma same argon same silane same VHF same (silicon or Si) and silicon with (diffuse diffusing diffused diffusion)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/10/14 12:39